

Micromechanical Piezoelectric Actuators for Implementing Large Forces and Deflections

Abstract

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Embodiments of the present invention provide a MEMS comprising a diaphragm, a stroke structure coupled to the diaphragm, and at least two piezoelectric actuators coupled to a plurality of mutually spaced-apart contact points of the stroke structure via a plurality of mutually spaced-apart connecting elements, the at least two piezoelectric actuators being

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configured to cause a stroke movement of the stroke structure so as to deflect the diaphragm.

Figure for abstract: Fig. 1a